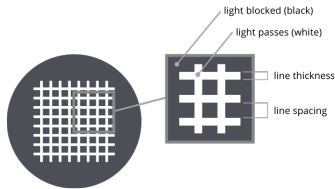


Grid pattern, Photolithography



SPECIFICATIONS

Type	Grid	
Process	Photolithography	
Substrate	Soda lime glass	
Coating	Chrome on glass	
Line spacing	(mm)	0.05
Line thickness	(mm)	0.05
Dot size	(mm x mm)	-
Geometrical accuracy	(μm)	2
Edge sharpness	(μm)	1.4

Circular aperture (LTPR)

Active Area	(mm)	11
Number of lines		110 x 110
Max line length	(mm)	11

Square aperture (LTPRSM)

Active Area	(mm)	8 x 8
Number of lines		80 x 80
Max line length	(mm)	8

Mechanical specifications

Diameter	(mm)	21
Thickness	(mm)	1.6

COMPATIBLE PRODUCTS

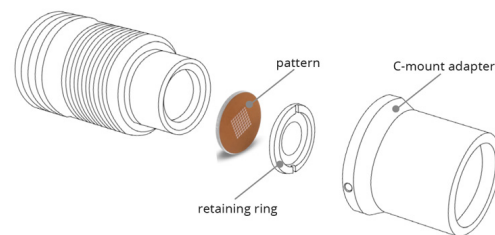
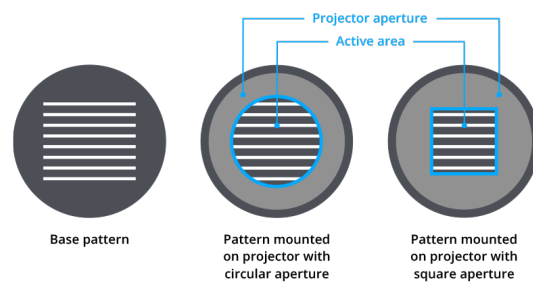
Full list of compatible products available [here](#).



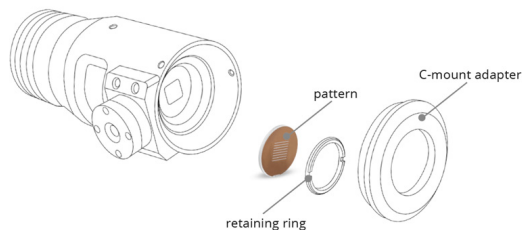
A wide selection of innovative machine vision components.

Opto Engineering® supplies a comprehensive range of projection patterns compatible with our LED illuminators. PT projection patterns can be either laser-engraved, with 50 μm geometrical accuracy, or photolithography-engraved for more demanding applications (2 μm accuracy).

PTPR AND ACTIVE AREA



Pattern projector with circular aperture disassembled.



Pattern projector with square aperture disassembled.